

AMENDMENTS TO THE SPECIFICATION:

Please replace paragraph [0006] that was added in the Amendment filed on August 15, 2005, with the following amended paragraph:

[0006] A preferred embodiment of a component of a plasma processing apparatus comprises a ~~first part~~ second member including an attachment surface and an exposed surface adapted to be exposed to an interior of a plasma processing chamber; a ~~second part~~ first member including a first surface spaced from a second surface, the first surface being bonded to the attachment surface of the ~~first part~~ second member, the ~~second part~~ first member including axially extending apertures extending between the first surface and the second surface, each of the apertures including a first portion opening in the first surface and a second portion opening in the second surface, the first portion being wider in a transverse direction than the second portion; and fastener members located in the second portions of the apertures. The ~~first part~~ second member can be a showerhead electrode and the ~~second part~~ first member can be a backing plate.

Please replace original paragraph [0006] with the following amended paragraph:

[0006] A preferred embodiment of a method of making a component for a plasma processing apparatus comprises securing a ~~first part~~ member, such as a backing member to a ~~second part~~ member, such as an electrode. The ~~first part~~ member includes a plurality of apertures including a first portion and a wider second portion. A first fastener member is mounted in each aperture. The first fastener members preferably include a head in the second portion of the aperture. The head is

preferably configured to prevent the first fastener member from being pulled out of the aperture, or from rotating.

Please replace paragraph [0021] with the following amended paragraph:

[0021] FIG. 1 depicts a preferred embodiment of an upper electrode assembly 10, which comprises an upper electrode preferably including an inner electrode member 12, and an outer electrode member 14. Herein, the ~~inner electrode member 12 is also described as a "second member" and as a "first part"; and the inner electrode member 12 and the outer electrode member 14 are upper electrode is also described referred to as comprising a "second member."~~ A lower electrode 15 is shown positioned below the upper electrode. In an embodiment, the inner electrode member 12 is preferably a cylindrical plate. The outer electrode member 14 can be continuous member (e.g., a poly-silicon member, such as a ring), or can alternatively include multiple segments (e.g., 2-6 segments). In embodiments including a multiple-segment outer electrode member 14, contiguous segments preferably overlap each other to protect the underlying joint, such as an elastomeric joint, from exposure to plasma.

Please replace paragraph [0024] with the following amended paragraph:

[0024] The backing member preferably includes a backing plate 18, which is co-extensive with the inner electrode member 12, and an outer backing ring 22. Herein, ~~the backing plate 18 is also described as a "first member" and as a "second part"; and the backing plate 18 and backing ring 22 are member is also described referred to as comprising a "first member."~~ The backing member is preferably made of

graphite. The top surface 16 of the inner electrode member 12 is preferably bonded to a bottom surface 19 (or "first surface") of the backing plate 18 (see FIG. 1), and the top surface 20 of the outer electrode member 14 is preferably bonded to a continuous backing ring 22. The backing plate 18 also has a top surface 21 (or "second surface"), as shown in FIGS. 1 and 6.

Please replace paragraph [0025] with the following amended paragraph:

[0025] The backing plate 18 and backing ring 22 are attached to a top plate 24. Herein, the top plate 24 is also referred to as a "third part member." The top plate 24 is preferably temperature controlled by flowing a heat transfer fluid (liquid or gas) through it. The top plate 24 is preferably made of a metal having suitable thermal conductivity, such as aluminum, or an aluminum alloy. The top plate 24 preferably provides an electrical ground and a heat sink for the electrode. Preferably, a vacuum seal is provided between the top plate 24 and the backing plate 18 and/or backing ring 22. For example, a sealing member, such as a sealing ring 26, can be located between the backing plate 18 and the top plate 24 to minimize gas leakage through an interface between the inner electrode member 12 and the outer electrode member 14.

Please replace paragraph [0041] with the following amended paragraph:

[0041] FIG. 10 depicts another preferred embodiment of an upper electrode assembly including an alternative fastening arrangement. A fastener member 128 is received in an aperture 136 in the backing ring 22, and in an opening 132 in the top plate 24 (the backing plate 18, inner electrode member 12, and associated portion of

the top plate 24 are not shown for simplicity). The fastener member 128 includes a head 129 and a shaft 130. The shaft 130 preferably includes external threads 131 at an upper portion 131 133. A fastener member 140, such as a threaded nut, engages the threads 131 to secure the top plate 24 to the backing ring 22 and to the outer electrode member 14.